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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 08/846,671
Filing Date April 30, 1997
Inventor Kei-Yu Ko
Assignee..... Micron Technology, Inc.
Group Art Unit..... 1763
Examiner George Goudreau
Attorney's Docket No. MI22-2041
Title: Undoped Silicon Dioxide as Etch Stop for Selective Etch of
Doped Silicon Dioxide

RESPONSE TO MARCH 3, 2003 CONFERENCE WITH EXAMINER AND
SUPPLEMENTAL RESPONSE TO DECEMBER 5, 2002 OFFICE ACTION

To: Commissioner for Patents
Washington, D.C. 20231 VIA EXPRESS MAIL

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)
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Responsive to the Conference with the examiner, held on March 3,
2003, Applicant amends and remarks as follows:

AMENDMENTS